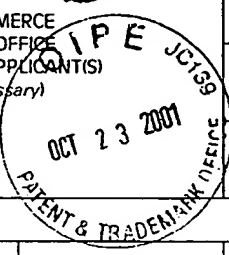
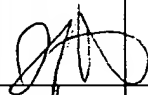
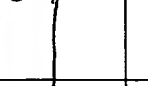


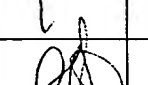



FORM PTO 1449 (modified) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary) Date Submitted to PTO: October 23, 2001			ATTY DOCKET NO. 862.C2183		APPLICATION NO. 09/819,737										
			APPLICANT Haruhiro ONO, et al.												
			FILING DATE March 29, 2001												
			GROUP 2812 2822												
U.S. PATENT DOCUMENTS															
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE								
X															
FOREIGN PATENT DOCUMENTS															
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT								
X															
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)															
	"Sub-Nanometer Miniature Electron Microscope", A.D. Feinerman, et al., Journal of Vacuum Science and Technology A, Vol. 10, No. 4, July/August 1992, 611-616.														
	"High Aspect Ratio Aligned Multilayer Microstructure Fabrication", K. Y. Lee, et al., Journal of Vacuum Science and Technology B, Vol. 12, No. 6, November/December 1994, pp. 3425-3430.														
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				DATE CONSIDERED 6-19-02											

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered.

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Sheet 2 of 2

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Date Submitted to PTO: October 23, 2001

ATTY DOCKET NO.

862.C2183

APPLICATION NO.

09/819,737

APPLICANT

Haruhiro ONO, et al.

FILING DATE

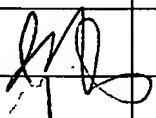

March 29, 2001

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U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	5,834,783	11/10/1998	Muraki, et al.	250	398	
	5,864,142	01/26/1999	Muraki, et al.	250	491.1	
	5,905,267	05/18/1999	Muraki	250	492.22	
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OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

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6/19/02

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